



Biography

Vivek Bakshi

EUV Litho, Inc.

Dr. Vivek Bakshi is founder and president of EUV Litho, Inc., an organization he formed in 2007 to promote EUV Lithography via consulting, workshops and education. He provides consulting services in the areas of EUV lithography (EUVL) and general lithography to investors, funding agencies, universities, national labs and suppliers. He also organizes the annual International Workshop on EUV Lithography and annual International Workshop on EUV and Soft X-ray Sources. He teaches EUVL short courses around the world.

Since July 2012, Dr. Bakshi has served as an *Adjunct Associate Professor* in the School of Physics, University College Dublin, Ireland. He is a member of the Editorial board and Associate Editor of JM3 (SPIE Journal of Micro/Nano Lithography, MEMS and MOEMS). He frequently blogs about EUVL and his latest blog "EUVL FOCUS" for magazine *Solid State Technology* can be read at <http://www.electroiq.com/blogs/euvl-focus.html>. He is widely quoted in trade media on EUVL-related topics and he is an internationally recognized expert on EUV source technology and EUV lithography. Previously, he was a *Senior Member of the Technical Staff* in SEMATECH's Lithography Division.

Dr. Bakshi has authored/co-authored over 125 technical publications, including book chapters, articles in peer-reviewed journals, technical reports, and trade publications. He has edited three books on EUVL: ***EUV Sources for Lithography*** (SPIE Press, 2006), ***EUV Lithography*** (SPIE Press, 2008) and ***Extreme Ultraviolet Lithography*** (SPIE Press, 2012 (co-edited with Anthony Yen)). He holds three US patents in the area of EUVL.

Contact Information:

Dr. Vivek Bakshi
President, EUV Litho, Inc.
www.euvlitho.com
vivek DOT bakshi AT euvlitho DOT com

Mailing Address:
EUV Litho, Inc.
10202 Wommack Road, Austin, TX 78748 USA

